



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

For 1732

In re application of:

Group Art Unit: 1732

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Richard S. Harris, Kevin P. Fahey,  
Lian-Cheng Zou, and Thomas R. McNeil**

Application No. 10/017,497

Filed: December 14, 2001

For: **ULTRAVIOLET LASER ABLATIVE  
PATTERNING OF MICROSTRUCTURES  
IN SEMICONDUCTORS**

Date: February 4, 2005

Examiner: Dr. Stefan Staicovici

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AMENDMENT A

TO THE COMMISSIONER FOR PATENTS:

In response to the October 4, 2004 Office action, please amend the above-identified application as follows.

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims that begins on page 3 of this paper.

**Remarks** begin on page 12 of this paper.

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